



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Fumio SAKIYA et al.

Group Art Unit: 2121

Application No.: 10/516,337

Examiner: D. ROBERTSON

Filed: August 5, 2005

Docket No.: 121933

For: METHOD AND SYSTEM FOR TEACHING REFERENCE POSITION OF
SEMICONDUCTOR WAFER IN AUTOMATED WAFER HANDLING
MANUFACTURING EQUIPMENT (AS AMENDED)

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the October 5, 2010 Office Action, please consider the following:

Amendments to the Specification;

Amendments to the Claims as reflected in the listing of claims;

Amendments to the Drawings include an attached replacement sheet; and

Remarks.